



Gases and Facilities Japan Joint TC Chapter Meeting Summary and Minutes

SEMI Japan Standards Spring 2018 Meetings
November 30, 2018, Begin [14:00] – End [17:00]
SEMI Japan, Tokyo, Japan

TC Chapter Announcements

Next TC Chapter Meeting

Gases and Facilities Japan Joint TC Chapter

April 12, 2019, Begin [15:00] – End [17:00]

SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Italics indicate virtual participants

Gases Japan TC Chapter Co-Chairs: Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan)

Facilities Japan TC Chapter Co-Chairs: Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan)

SEMI Staff: Mizue Iwamura

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Ball Wave	Tsukahara	Yusuke	<i>Hitachi High-Technologies</i>	<i>Enami</i>	<i>Hiromichi</i>
Consultant	Suzuki	Isao	NISSAN TANAKA	Takamisawa	Kazuhiko
Daido Steel	Matsuda	Mitsuhiro			
Fujikin	Kitano	Masafumi	SEMI Japan	Iwamura	Mizue

Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
<i>Gases Japan TC Chapter</i>		
None.		
<i>Facilities Japan TC Chapter</i>		
None.		



Table 3 Committee Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
<i>Gases Japan TC Chapter</i>	
None.	
<i>Facilities Japan TC Chapter</i>	
None.	

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
<i>Gases Japan TC Chapter</i>		
None.		
<i>Facilities Japan TC Chapter</i>		
6395	Revision to SEMI F1-0812, Specification for Leak Integrity of High Purity Gas Piping Systems and Components	Failed , returned to TF for rework

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Activities Approved by the GCS between meetings of the TC Chapter

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
<i>Gases Japan TC Chapter</i>			
None.			
<i>Facilities Japan TC Chapter</i>			
None.			

Table 6 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
<i>Gases Japan TC Chapter</i>			
None.			
<i>Facilities Japan TC Chapter</i>			
None.			

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARE>



Table 7 Authorized Ballots

#	When	TF	Details
<i>Gases Japan TC Chapter</i>			
None.			
<i>Facilities Japan TC Chapter</i>			
6395A	Cycle 4 or 5, 2019	F1 revision TF	Revision to SEMI F1-0812, Specification for Leak Integrity of High Purity Gas Piping Systems and Components

Table 8 SNARF(s) Granted a One-Year Extension

#	TF	Title	Expiration Date
<i>Gases Japan TC Chapter</i>			
None.			
<i>Facilities Japan TC Chapter</i>			
None.			

Table 9 SNARF(s) Abolished

#	TF	Title
<i>Gases Japan TC Chapter</i>		
None.		
<i>Facilities Japan TC Chapter</i>		
None.		

Table 10 Standard(s) to receive Inactive Status

Standard Designation	Title
<i>Gases Japan TC Chapter</i>	
None.	
<i>Facilities Japan TC Chapter</i>	
None.	

Table 11 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
None.		

Table 12 Previous Meeting Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
20180424_01	Mizue Iwamura (SEMI Japan)	To make the list of SEMI Standards which originating TC chapter are Japan Gases and Facilities. Closed Mizue Iwamura (SEMI Japan) provide the document list as attached. Attachment: 20181120_G&F_Standards_OTC_Japan
20180424_02	Tetsuo Shimizu (HORIBA STEC)	To provide the past 3 years activities reports of Live Gas Flow Rate Task Force. OPEN

1 Welcome, Reminders, and Introductions

Isao Suzuki (MKS Japan) called the meeting to order at 14:10. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01-02_SEMI Standards Required Elements_August2018_E+J

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion: To approve the minutes of the previous meeting as written.

By / 2nd: Masafumi Kitano (Fujikin) / Kazuhiko Takamisawa (NISSAN TANAKA)

Discussion: None.

Vote: 4 in favor and 0 opposed. **Motion passed.**

Attachment: 02-00_20180629_Minutes_Draft_Gases and Facilities_r1

3 Liaison Reports

3.1 Facilities North America TC Chapter

Mizue Iwamura (SEMI Japan) reported for the Facilities North America TC Chapter as attached.

Attachment: 03-01&02_NA F&G Liaison Report Nov2018 v1



3.2 *Gases North America TC Chapter*

Mizue Iwamura (SEMI Japan) reported for the Gases North America TC Chapter as attached.

Attachment: 03-01&02_NA F&G Liaison Report Nov2018 v1

3.3 *Gases Europe TC Chapter*

None.

3.4 *Facilities Korea TC Chapter*

None.

3.5 *Semiconductor Components, Instruments, and Subsystems Technology Community (SCIS)*

Mizue Iwamura (SEMI Japan) gave the Semiconductor Components, Instruments, and Subsystems Technology Community (SCIS) Report as attached.

Attachment: 03-05_SEMI SCIS Overview 2018Nov27

3.6 *Electronic Materials Group (EMG)*

Mizue Iwamura (SEMI Japan) gave the Electronic Materials Group (EMG) Report as attached.

Attachment: 03-06_Overview of SEMI Electronic Materials Group - Nov2018

3.7 *SEMI Staff Report*

Mizue Iwamura (SEMI Japan) gave the SEMI Staff Report as attached.

Attachment: 03-07_SEMI Staff Report 2018_1126

4 **Ballot Review**

NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

4.1 *Gases Japan TC Chapter*

None.



4.2 Facilities Japan TC Chapter

4.2.1 Document # 6395, Revision to SEMI F1-0812, Specification for Leak Integrity of High Purity Gas Piping Systems and Components

The ballot **failed** TC review, and it will be submitted as 6395A, Revision to SEMI F1-0812, Specification for Leak Integrity of High Purity Gas Piping Systems and Components. Details can be found in the attached Procedural Review file for Cycle 4 or 5, 2019.

Attachment: 04-01_6395_Ballot report template with Technical Change Rev3

5 Subcommittee and Task Force Reports

5.1 Gases Japan TC Chapter

None.

5.2 Facilities Japan TC Chapter

5.2.1 F1 Revision Task Force

Masafumi Kitano (Fujikin) reported for the F1 Revision Task Force as attached.

Attachment: 05-02-1_2018119_F1 TF report_r3

Motion: To approve a ballot submission of 6395A, Revision to SEMI F1-0812, Specification for Leak Integrity of High Purity Gas Piping Systems and Components for Cycle 4 or 5, 2019.

By / 2nd: Masafumi Kitano (Fujikin) / Kazuhiko Takamisawa (NISSAN TANAKA)

Discussion: None.

Vote: 4 in favor and 0 opposed. **Motion passed.**

5.2.2 5-year-review Task Force

Masfumi Kitano (Fujikin) reported that there are no activities currently working on.

6 Old Business

6.1 Gases Japan TC Chapter

6.1.1 SNARF Project Period Check

Mizue Iwamura (SEMI Japan) addressed that there is no SNARF that exceed the project period.

6.1.2 5 Year Review Check

Mizue Iwamura (SEMI Japan) addressed that there is no document to be addressed.

6.2 Facilities Japan TC Chapter

6.2.1 SNARF Project Period Check

Mizue Iwamura (SEMI Japan) addressed that there is no SNARF that exceed the project period.



6.2.2 5 Year Review Check

Mizue Iwamura (SEMI Japan) addressed that there is no document to be addressed.

7 New Business

7.1 Gases Japan TC Chapter

None.

7.2 Facilities Japan TC Chapter

7.2.1 Future revision plan for “F20-0706E (Reapproved 0917), Specification for 316L Stainless Steel Bar, Forgings, Extruded Shapes, Plate, and Tubing for Components Used in General Purpose, High Purity and Ultra-High Purity Semiconductor Manufacturing Applications”

Hiromichi Enami reported for the information about the next focusing items in the Gases & Facilities Committee. For the F20 revision, we expect Japanese steel suppliers to join the discussion.

7.2.2 Topics of “E176-1017, Guide To Assess and Minimize Electromagnetic Interference (EMI) in a Semiconductor Manufacturing Environment” at NA Facilities TC Chapter

Hiromichi Enami reported for this topic as attached.

Attachment: 07-02-2_181130_E176 Related Information V02

7.2.3 New Co-chair appointment

Isao Suzuki (Consultant) addressed to the committee on this topic.

Motion: To approve an appointment of Masafumi Kitano (Fujikin) as co-chair.

By / 2nd: Kazuhiko Takamisawa (NISSAN TANAKA) / Yusuke Tsukahara (Ball Wave)

Discussion: None.

Vote: 4 in favor and 0 opposed. **Motion passed.**

8 Next Meeting and Adjournment

The next meeting is scheduled at 3 p.m. for April 12, 2019 at SEMI Japan, Tokyo, Japan.

See <http://www.semi.org/standards-events> for the current list of events.

Adjournment: [17:00].

Respectfully submitted by:

Mizue Iwamura

Coordinator

SEMI Japan



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Email: miwamura@semi.org

Minutes tentatively approved by:

Hikomichi Enami (Hitachi High-Technologies), Gases Japan TC Chapter Co-chair	December 25, 2018
Isao Suzuki (MKS Japan), Gases Japan TC Chapter Co-chair	December 25, 2018
Hikomichi Enami (Hitachi High-Technologies), Facilities Japan TC Chapter Co-chair	December 25, 2018
Isao Suzuki (MKS Japan), Facilities Japan TC Chapter Co-chair	December 25, 2018

Table 13 Index of Available Attachments^{#1}

<i>Title</i>	<i>Title</i>
01-02_SEMI Standards Required Elements_August2018_E+J	04-01_6395_Ballot report template with Technical Change Rev3
02-00_20180629_Miniutes_Draft_Gases and Facilities_r1	05-02-1_2018119_F1 TF report_r3
03-01&02_NA F&G Liaison Report Nov2018 v1	07-02-2_181130_E176 Related Information V02
03-05_SEMI SCIS Overview 2018Nov27	20181120_G&F_Standards_OTC_Japan
03-06_Overview of SEMI Electronic Materials Group - Nov2018	
03-07_SEMI Staff Report 2018_1126	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.